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ムンフェエ PATENT TRADEMARK OFFICE

July 10, 2003

Mail Stop PATENT APPLICATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 Re: New U.S. Patent Appln. Our Ref: 010986.52578US

Sir:

Transmitted herewith for filing is the patent application of:

Hideaki YAMASAKI and Yumiko KAWANO

entitled:

Film-Formation Apparatus and Source Suplying Apparatus Therefor, Gas Concentration Measuring Method

Enclosed are:

- 1. Specification, including $\underline{29}$ claims (pages $\underline{55}$).
- 2. <u>16</u> Sheets of Formal drawings showing Figs. 1-16.
- 3. Declaration and Power of Attorney.
- 4. Application Data Sheet
- 5. Assignment of the invention to <u>Tokyo Electron Limited</u>
- 6. Priority is being claimed under 35 U.S.C. §119 and 37 C.F.R. §1.55 based on Priority Document 2002-201532, filed in <u>Japan</u> on <u>July 10, 2002</u> and. Priority Document 2003-191044, filed in <u>Japan</u> on <u>July 3, 2003</u>
- 7. The filing fee has been calculated as shown below:

 Basic Fee
 \$375/750 = \$750.00

 Total Claims
 29 - 20 = 9 x
 \$9/18 = \$162.00

 Independent Claims
 4 - 3 = 1 x
 \$42/84 = \$84.00

 Multiple Dependent Claim Presented
 \$140/280 = \$

 Total Filing Fee
 \$996.00

Two checks, one in the amount of \$996.00 for the filing fee and \$40.00 for the Assignment recording fee are enclosed. The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Deposit Account No. 05-1323 (Docket #010986.52578US). A duplicate copy of this sheet is enclosed.

Respectfully submitted,

335/9

Herbert I. Canton

HIC:tcv